Intro to MEMS

Last Updated: Tue, 03/17/2026

Course prefix: CHBE

Course number: 6229

Section: A

CRN
86750

Instructor first name: Peter

Instructor last name: Hesketh

Semester: Fall

Academic year: 2026

Course description: Introduction to Micro-Electro-Mechanical Systems: Microfabrication techniques including: photolithography, etching, physical and chemical vapor deposition, electroplating, bonding and polymer processing. Application to sensors and actuators.

Academic honesty/integrity statement:

Students are expected to maintain the highest standards of academic integrity. All work submitted must be original and properly cited. Plagiarism, cheating, or any form of academic dishonesty will result in immediate consequences as outlined in the university's academic integrity policy.

While students may collaborate on the weekly homework problems, any work turned in must be submitted individually by each student. Copying directly from classmates is not allowed. No collaboration of any kind, whether verbal, non-verbal, electronic or in-person, will be permitted on the exams.

Core IMPACTS statement(s) (if applicable):

This is a Core IMPACTS course that is part of the Mathematics area.

Core IMPACTS refers to the core curriculum, which provides students with essential knowledge in foundational academic areas. This course will help master course content, and support students’ broad academic and career goals.

This course should direct students toward a broad Orienting Question:

How do I measure the world?

Completion of this course should enable students to meet the following Learning Outcome:

Students will apply mathematical and computational knowledge to interpret, evaluate, and communicate quantitative information using verbal, numerical, graphical, or symbolic forms.

Course content, activities and exercises in this course should help students develop the following Career-Ready Competencies:

Information Literacy

Inquiry and Analysis

Problem-Solving